

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S29	4	(US-5434026-\$ or US-5617203-\$ or US-5742395-\$ or US-6535628-\$).did.	USPAT	OR	OFF	2006/10/17 15:16
S31	4255	(chamber same (wafer)) and (develop\$6 same chamber)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/17 15:31
S30	3	S29 and sensor\$2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/17 15:31
S33	167	S32 and (sensor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/17 15:32
S32	409	S31 and (imager or ccd or camera\$2 or (image adj collector))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/17 15:32
S34	34	S33 and ((imager or ccd or camera\$2 or (image adj collector)) same chamber)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/17 15:33
S35	5	("5843527").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 09:21
S36	1081	(camera\$2 or imager\$2 or ccd) and (silicon adj waf\$5) and (developer\$2 or expos\$6 or spin) and (sensor\$2 same (defect or error\$2 or malfunction or quality))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 11:38
S38	19	((camera\$2 or imager\$2 or ccd) same ((develop\$5 or expos\$6 or spin) same (chamber or unit or housing))) and (silicon adj waf\$5) and (developer\$2 or expos\$6 or spin) and (sensor\$2 same (defect or error\$2 or malfunction or quality))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 11:40

EAST Search History

S39	10	("4647172" "4851311" "5244501" "5366757" "5653811" "5843527" "5940175" "5962193" "5985357" "5995218").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2006/10/24 11:45
S40	33	("5940175").URPN.	USPAT	OR	OFF	2006/10/24 15:19
S9	1666153	(chamber or (spin adj (unit or chamber)) or (processing adj (unit or chamber)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:20
S6	2	("5991426").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:20
S46	36506	((silicon or semiconductor\$2) near2 (wafer\$2 or substrate)) and ((develop\$8 or expose\$4 or exposur\$6) same (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:26
S41	48207	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and ((develop\$8 or expose\$4 or exposur\$6) same (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:26
S50	1040	S49 and sensor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:27
S45	452	S44 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:27
S44	1444	S43 and sensor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:27
S43	2286	S42 and ((imager or ccd or camera\$2 or (imag\$5 or picture\$3) near2 device)) same (unit or chamber))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:27

EAST Search History

S42	24310	S41 and (inspect\$6 or error\$2 or malfunction or quality)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:27
S49	1639	S48 and ((imager or ccd or camera\$2 or ((imag\$5 or picture\$3) near2 device)) same (unit or chamber))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:28
S48	18917	S47 and (inspect\$6 or error\$2 or malfunction or quality)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:28
S47	38705	((silicon or semiconductor\$2) near2 (wafer\$2 or substrate)) and ((develop\$8 or expose\$4 or exposur\$6 or spin) same (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:28
S51	277	S50 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:29
S57	4008	((silicon or semiconductor\$2) near2 (wafer\$2 or substrate)) and ((develop\$8 or spin) near4 (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:42
S53	6421	S52 and (inspect\$6 or error\$2 or malfunction or quality)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:42
S52	12290	((silicon or semiconductor\$2) near2 (wafer\$2 or substrate)) and ((develop\$8 or expose\$4 or exposur\$6 or spin) near4 (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:42
S62	68	S61 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43
S61	255	S60 and ((imager or ccd or camera\$2 or ((imag\$5 or picture\$3) near2 device)) same (unit or chamber))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43

EAST Search History

S60	1509	S58 and ((inspect\$6 or error\$2 or malfunction or quality) same (wafer\$2 or substrate\$2))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43
S56	113	S55 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43
S55	457	S54 and ((imager or ccd or camera\$2 or ((imag\$5 or picture\$3) near2 device)) same (unit or chamber))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43
S54	4174	S52 and ((inspect\$6 or error\$2 or malfunction or quality) same (wafer\$2 or substrate\$2))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 15:43
S63	46	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and (((develop\$8 or spin) near4 (chamber or unit)) same (imager or camera\$2 or ccd or ((imag\$5 or picture\$2) adj (unit or device))))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 19:25
S64	20	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and (((develop\$8) near4 (chamber)) same (imager or camera\$2 or ccd or optical or ((imag\$5 or picture\$2) adj (unit or device))))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/24 19:27
S58	5153	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and ((develop\$8 or spin) near4 (chamber or unit))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 08:46
L2	46	1 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 08:49
L1	150	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and (chamber same (camera or ccd or imager)) and (chamber same (sensor\$2 same (pressure or temperature or vibration or (rotation adj speed) or rpm)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:04

EAST Search History

L3	241	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and (chamber same (camera or ccd or imager) same sensor\$2)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:05
L6	28	5 not 2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:06
L5	56	3 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:06
L4	2039	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and ((chamber or unit) same (camera or ccd or imager) same sensor\$2)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:35
L7	4	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and (((spin or develop\$6 or coat\$6) near3 unit) same (camera or ccd or imager) same sensor\$2)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 10:43

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L8	394	(chamber and (imager or ccd or camera\$2) and sensor\$2).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 11:32
L9	82	((silicon or semiconductor\$2) same (wafer\$2 or substrate)) and 8	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 11:32
L10	18	9 and @ay<"2001"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/26 11:33